



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

in re the Application of: **ONO, Yuji et al.**

Group Art Unit: 1746

Serial No.: **09/940,788**

Examiner: **Joseph L. Perrin**

Filed: **August 29, 2001**

P.T.O. Confirmation No.: 4613

For: **SINGLE WAFER TYPE SUBSTRATE CLEANING METHOD AND APPARATUS**

AMENDMENT ACCOMPANYING REQUEST FOR CONTINUED EXAMINATION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

November 9, 2005

Sir:

This Amendment is responsive to the Office Action dated **August 15, 2005**, and is being filed concurrently with a Request for Continued Examination (RCE). Please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.